OCT 2 2 2004 CHARLES Attorney Docket No. P68-US

Jew 1763

**PATENT** 

#### IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Satyadev R. Patel et al.

Art Unit:

1763

Serial No.: 09/954,864

Examiner:

Olsen, Allan

Filed: September 17, 2001

For: METHOD FOR ACHIEVING IMPROVED SELECTIVITY IN AN ETCHING

**PROCESS** 

#### INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.97(b)

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

The attention of the Patent and Trademark Office is herby directed to the documents listed on the attached PTO form 1449. Copies of the cited references are enclosed.

This Information Disclosure Statement is being submitted after issuance of a first official action on the merits and expiration of the three month period following filing of the above-captioned application, but prior to issuance of either a final official action or a Notice of Allowance. The \$180 fee set forth in 37 CFR Section 1.17(p) is enclosed.

The above information is presented so that the Patent and Trademark Office can determine any materiality thereof to the claimed invention. It is respectfully requested that the information be expressly considered during the prosecution of this application.

## Attorney Docket No. P68-US

The Commissioner is hereby authorized to charge any additional fee (or credit any overpayment) associated with this statement to our Deposit Account No. 501516.

Respectfully submitted,

Gregory R. Muir

Attorney for Applicant(s) Registration No. 35,293

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PTO/SB/08A (10-01)

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				Application Number	09/954.864	
INFO	RMATION	I DIS	SCLOSURE	Filing Date	9/17/01	
STAT	EMENT E	BY A	PPLICANT	First Named Inventor	Patel	
				Art Unit	1763	
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Sheet	1	of	6	Attorney Docket Number	P68-US	

		,	U.S. PAT	ENT DOCUMENTS	
Examiner Initials		Document Number  Number - Kind Code <sup>2</sup> (if known	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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Substitute for form 1449A/PTO

## **INFORMATION DISCLOSURE** STATEMENT BY APPLICANT

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Complete if Known				
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Examiner Name	Olsen. Allan			
Attorney Docket Number	P68-US			

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Sheet	3	of	6	Attorney Docket Number	P68-US	

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(use as many sheets as necessary)				Examiner Name	Olsen. Allan	
Sheet	4	of	6	Attorney Docket Number	P68-US	

Examiner Initials	Cite No.1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.					
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Complete if Known Substitute for form 1449B/PTO 09/954,864 **Application Number INFORMATION DISCLOSURE** 9/17/01 Filing Date **First Named Inventor** STATEMENT BY APPLICANT Patel **Group Art Unit** 1763 Olsen, Allan **Examiner Name** (use as many sheets as necessary) **Attorney Docket Number** of P68-US Sheet 6

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		SEBEL et al., "Reaction Layer Dynamics in Ion-Assisted Si/XeF2 Etching: Temperature Dependence", J. Vac. Sci. Technol. A, Vac. Surf. Films, Vol. 18, No. 6, (Nov. 2000), pp. 2759-2769 (abstract only).		
- 40 <b>16 - 10 4</b> 01 <b>6 1</b> 00		SEBEL et al., "Silicon Etch Rate Enhancement by Traces of Metal", J. Vac. Sci. Technol. A, Vac. Surf. Films, Vol. 17, No. 3, (May/June 1999), pp. 755-762 (abstract only).	e also Security and	
		SUGANO et al., "Study on XeF2 Pulse Etching Using Wagon Wheel Pattern", Proceedings of the 1999 International Symposium on Micromechantronics and Human Science: Towards the New Century, Nagoya, Japan (Nov. 23 - 26, 1999), pp. 163-167 (abstract only).		
		WANG et al., "Gas-Phase Silicon Etching with Bromine Trifluoride", International Solid State Sensors and Actuators Conference (Transducers '97), Chicago, IL, Vol. 2 (June 16 - 19, 1997), pp. 1505-1508 (abstract only).		
		MUTHUKUMARAN et al., "Gas-Phase Xenon Difluoride Etching of Microsystems Fabricated Through the Mitel 1.5-mu m CMOS Process", Can. J. Electr. Comput. Eng. (Canada), Vol. 25, No. 1 (Jan. 2000), pp. 35-41 (abstract only).		
		TODA et al., "Thin Beam Bulk Micromachining Based on RIE and Xenon Difluoride Silicon Etching", International Solid State Sensors and Actuators Conference (Transducers '97), Chicago, IL, Vol. 1 (June 16 - 19, 1997), pp. 671-674.		
		SEBEL et al., "Etching of Si Through a Thick Condensed XeF2 Layer", J. Vac. Sci. Technol. A, Vac. Surf. Films, Vol 18, No. 5 (Sept/Oct 2000), pp. 2090-2097 (abstract only).		
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